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#### REMARKS/ARGUMENT

Applicant responds herein to the Office Action dated August 9, 2002. A Petition for Extension of Time (one month) and the fee therefor are enclosed.

Claims 24-27 have been formally allowed.

Claims 5-7, 10-13, 16-19, 22 and 23 have been objected to, but indicated to be allowable. Responsive to the foregoing indication, the applicant has amended claims 1, 7, 10 and 11 and has canceled claims 5 and 6, in a manner which casts claims 1-4 and 7-13 into allowable form. An indication of the allowance of these claims is earnestly solicited.

Similarly, rejected claim 21 has been cast in allowable form by incorporating into it, the same limitations which render claim 1 allowable. Formal allowance of claim 21 is therefore respectfully solicited.

Claim 22 has been indicated to be directed to patentable subject matter and that claim has been cast in independent form. This should result in claims 21-23 being added to the list of allowable claims.

Although claims 16-19 have been indicated to be directed to patentable subject matter, these dependent claims depend directly or indirectly from rejected claims 14 and 15 which are contended in the Office Action to be anticipated by Sando, et al. Reconsideration of the rejection of claims 14, 15 and 20 is requested, in view of the following remarks. The applicant prefers to defer the rendering of the allowable claims 16-19 into independent form pending resolution of the rejection of claims 14, 15 and 20.

Turning to the cited reference (U.S. Patent 4,437,324), it is noted at the outset that the claimed invention presented in independent claim 14, teaches at least two vertical chambers that are spaced apart and are independent of each other. Therefore, the two chambers can have, and do in fact permit, independent processing conditions. For example, one chamber may have a vacuum level, a reactive gas to be used, a flow rate of the gas, and so on, that are different than in the other chambers. The various processing condition in a chamber enable plasma polymerization to be controlled in a desired manner for a particular substance being treated.

The cited reference does not teach the aforementioned features of independent claim 14. The reference describes and concerns an apparatus for treating a cloth continuously with the use

of a low-temperature plasma. The apparatus in the cited reference comprises a reactor provided with seal mechanisms, where a plurality of partition walls are provided up and down alternately in the reactor to form zigzag cloth passages. The partitions provide only zigzag cloth passages, not independent spaces that are sealed from one another. Therefore, the reactor in the cited reference is for all practical purposes, a single chamber having a long passage, and certainly does not disclose or provide two passages which can support independent processing conditions.

Therefore, claim 14 was not properly asserted to be anticipated by the prior art. Nor is that claim rendered obvious by the prior art for the reasons noted above.

The dependent claims 15-20 include all of the aforementioned limitations discussed relative to claim 14 and impose further limitations which distances them even further from the prior art. Therefore, none of these claims can be said to be anticipated by the cited reference and all are indeed patentably distinguishable over the prior art. Therefore, claims 14-20 should be formally allowed as well.

Accordingly, the Examiner is respectfully requested to reconsider the application, allow the claims as amended and pass this case to issue.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner of Patents and Trademarks, Washington, D.C. 20231, on December 4, 2002

Max Moskowitz, Esq.
Name of applicant, assignee or
Registered Representative

Signature December 3, 2002

Date of Signature

Respectfully submitted,

Max Moskowitz

Registration No.: 30,576

OSTROLENK, FABER, GERB & SOFFEN, LLP

1180 Avenue of the Americas

New York, New York 10036-8403

Telephone: (212) 382-0700

MM:cg

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# APPENDIX B VERSION WITH MARKINGS TO SHOW CHANGES MADE 37 C.F.R. § 1.121(b)(iii) AND (c)(ii)

#### CLAIMS (with indication of amended or new):

1. (AMENDED) A continuous processing apparatus [by] <u>for plasma polymerization</u>, <u>the apparatus</u> having a plurality of chambers to perform a surface processing by plasma polymerization on [the] <u>a</u> surface of a substance being moved into a chamber, [comprising] <u>the apparatus comprising</u>:

at least one vertical chamber in which [a] the substance is vertically moved and at least one electrode [is] included therein[.];

wherein the vertical chamber includes substance pass holes formed at first and second sides thereof and/or top and bottom sides thereof.

7. (AMENDED) A continuous processing apparatus by plasma polymerization, the apparatus having a plurality of chambers to perform a surface processing by plasma polymerization on [the] a surface of [a] the substance being moved into a chamber, comprising:

at least one vertical chamber in which a substance is vertically moved and at least one electrode [is] included therein[,]:

[The apparatus of claim 1,] wherein as power is applied to the substance, the substance itself is used as an electrode.

10. (AMENDED) A continuous processing apparatus by plasma polymerization, the apparatus having a plurality of chambers to perform a surface processing by plasma polymerization on a surface of a substance being moved into a chamber, comprising:

at least one vertical chamber in which the substance is vertically moved and at least one electrode included therein;

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wherein the vertical chamber comprises:

a chamber body in which a substance is moved vertically, one side thereof being opened, a chamber door combined to the opened side of the chamber body; and

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at least one electrode disposed in parallel to the movement direction of the substance, [The apparatus of claim 8,] wherein the electrode is disposed at the chamber door.

11. (AMENDED) A continuous processing apparatus by plasma polymerization, the apparatus having a plurality of chambers to perform a surface processing by plasma polymerization on a surface of a substance being moved into a chamber, comprising:

at least one vertical chamber in which the substance is vertically moved and at least one electrode included therein;

[The apparatus of claim 1,] wherein the vertical chamber includes a partition plate at the center thereof, so that the vertical chamber is divided into two vertical areas by the partition plate.

21. (AMENDED) A continuous processing apparatus [by] <u>for</u> plasma polymerization with a vertical chamber, [including] <u>the apparatus comprising</u>:

an unwinding chamber having an unwinding roll for unwinding a substance wound thereon,

a winding chamber having a winding roll for winding a surface-processed substance, [and]

a polymerization chamber in which the substance is surface-processed by plasma discharging after being conveyed from the unwinding chamber, [wherein] the substance <u>being</u> [is] vertically [moved] <u>movable</u> in the polymerization chamber; and

at least one electrode included in the polymerization chamber[.];

wherein the vertical chamber includes substance pass holes formed at first and second sides thereof and/or top and bottom sides thereof.

22. (AMENDED) A continuous processing apparatus for plasma polymerization with a vertical chamber, the apparatus comprising:

an unwinding chamber having an unwinding roll for unwinding a substance wound thereon,

a winding chamber having a winding roll for winding a surface-processed substance,

a polymerization chamber in which the substance is surface-processed by plasma discharging after being conveyed from the unwinding chamber, the substance being vertically movable in the polymerization chamber; and

at least one electrode included in the polymerization chamber;

wherein the vertical chamber includes substance pass holes formed at first and second sides thereof and/or top and bottom sides thereof;

[The apparatus of claim 21, ] wherein the polymerization chamber comprises a chamber body having an electrode formed at the inner side thereof.